



IFW

PATENT  
Docket No. 20067/OPP031475

IN THE UNITED STATES PATENT  
AND TRADEMARK OFFICE

Applicant(s):

**Geon-Ook Park**

U.S. Serial No.: 10/748,652

For: "Method of Forming a Trench  
in a Semiconductor Device"

Filed: 12/30/2003

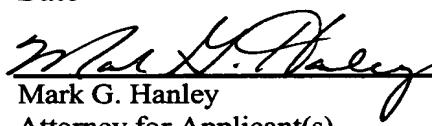
Group Art Unit: 2812

Examiner: Not Yet Assigned

) I hereby certify that this paper and the  
 ) documents referred to as enclosed  
 ) therewith are being deposited with the  
 ) United States Postal Service as first  
 ) class mail, postage prepaid, in an  
 ) envelope addressed to Commissioner  
 ) for Patents, P.O. Box 1450,  
 ) Alexandria, Virginia 22313-1450 on  
 ) this date:

June 31, 2005

Date

  
Mark G. Hanley  
Attorney for Applicant(s)  
Registration No. 44,736

STATUS LETTER

Commissioner for Patents  
P.O. Box 1450  
Alexandria, Virginia 22313-1450

Sir:

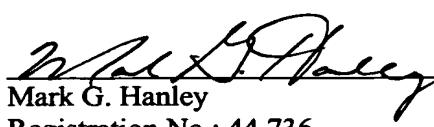
Kindly advise when an Office action can be expected in the above-referenced  
matter.

Respectfully submitted,

HANLEY, FLIGHT & ZIMMERMAN, LLC  
USPTO Customer Number 34431  
20 North Wacker Drive  
Suite 4220  
Chicago, Illinois 60606  
(312) 580-1020

6/21/05  
Date

By:

  
Mark G. Hanley  
Registration No.: 44,736